

Patent claims

1. A method for microstructuring by means of locally selective sublimation, where patterns or images of organic electroluminescent components are produced by applying a low-molecular emissions material on a support by means of sublimation to the areas of a substrate which correspond to a pattern or image to be produced, **characterized in that**
- first a film support (1) made from a temperature resistant material is completely coated with the emissions material,
 - the coated support (1) and the substrate (3) are then placed closely adjacent and parallel to each other in a vacuum chamber (4), where the side of the support (1) that is coated with the emissions material faces the substrate (3), and
 - on the side of the support (1) that is not coated, the areas corresponding to the pattern or image to be produced on the substrate (3) are then briefly and locally heated to a temperature that is sufficient for the sublimation of the emissions material.
2. A method as claimed in claim 1, **characterized in that** a polyimide film is used for the support (1).
3. A method as claimed in claim 1 or 2, **characterized in that** the support (1) is coated with two or more consecutive low-molecular layers in a way so that the different materials of the layers are not intermixed, while they form a mixed layer on the substrate (3) after the sublimation step.
4. A method as claimed in one of claims 1 to 3, **characterized in that** a structured electrical heating element is used to heat the support (1) locally.

5. A method as claimed in one of claims 1 to 3,
characterized in that laser radiation or lamp radiation in
conjunction with the corresponding optics are used to heat
5 the support (1) locally.

6. A method as claimed in claim 1, **characterized in that**
the low-molecular material is composed of materials which
improve the transport or the injection of electrical charge
10 carriers.

AMENDED CLAIMS

(The original claims 1 - 6 received on March 19, 2004 have been replaced by new claims 1 - 5 (2 pages)).

5 1. A method for microstructuring by means of locally selective sublimation, whereby patterns or images of organic electroluminescent components are produced by applying the emissions material on a support by means of sublimation to those areas of a substrate which correspond to a pattern or
10 image to be produced, where first a support (1) made of a temperature resistant material is completely coated with emissions material, and the coated support (1) and the substrate (3) are then placed closely adjacent and parallel to each other in a vacuum chamber (4) where the side of the
15 support (1) that is coated with the emissions material faces the substrate (3), and where the side of the support (1) that is not coated is then briefly and locally heated in the areas that correspond to the pattern or image to be produced on the substrate (3), to a temperature that is sufficient
20 for the sublimation of the emissions material, **characterized in that**

- the emissions material is a low-molecular emissions material, and
- the support (1) is coated with two or more
25 consecutive layers of different low-molecular materials in a way so that the different materials of the layers are not intermixed, while they form a mixed layer on the substrate (3) after the sublimation step.

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2. A method as claimed in claim 1, **characterized in that** a polyimide film is used for the support (1).

3. A method as claimed in claim 1 or 2, **characterized in that** a structured electrical heating element is used to heat the support (1) locally.
- 5 4. A method as claimed in claim 1 or 2, **characterized in that** laser radiation or lamp radiation in conjunction with the corresponding optics are used to heat the support (1) locally.
- 10 5. A method as claimed in claim 1, **characterized in that** the low-molecular materials are materials which improve the transport or the injection of electrical charge carriers.

Amended sheet (Article 19)